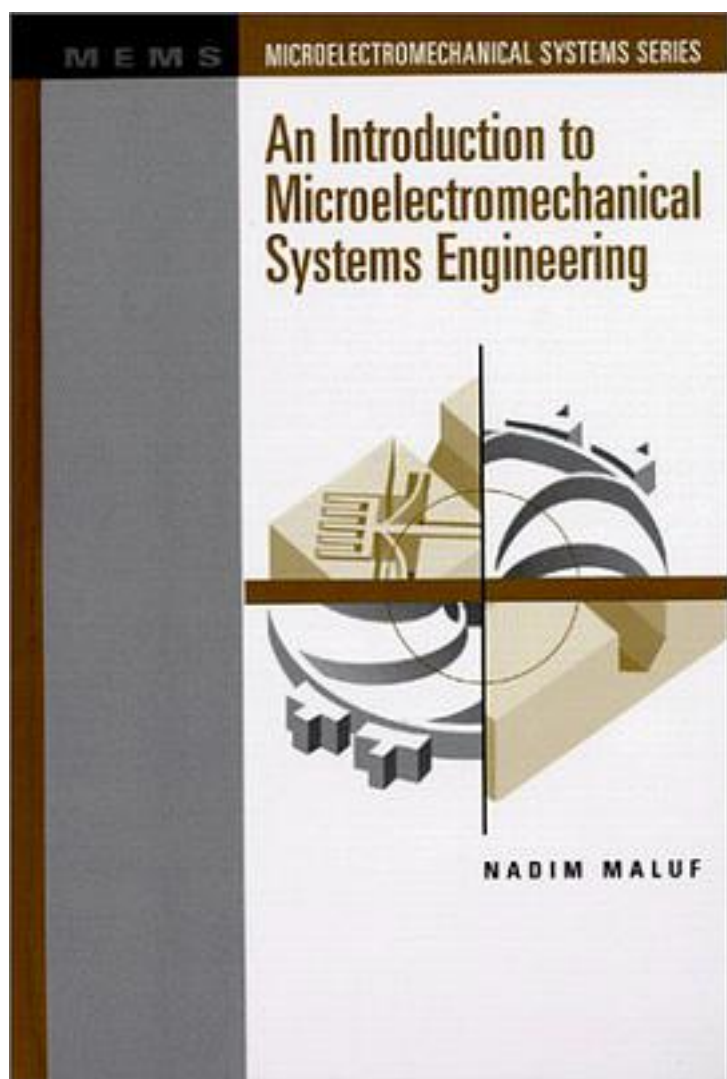


An Introduction to Microelectromechanical Systems Engineering



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A non-technical introduction to the field of microelectromechanical systems (MEMS). It describes in detail the materials used in producing MEMS - including silicon, polymers and glass and quartz substrates - as well as MEMS design for nozzles, sensors, valves and other applications. It examines the manufacture of commercial MEMS using technologies such as oxidation, lithography, chemical vapour deposition and silicon fusion bonding and applications in a wide range of industries including data storage, telecommunications, consumer, automotive, medical and defence. The book also addresses the future of MEMS - its potential for microelectrode arrays, actuators and optical switches and other technologies.

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